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CONFIRMATION NO. 2722

<b>SERIAL NUMBER</b> 10/587,039	<b>FILING or 371(c) DATE</b> 07/24/2006 <b>RULE</b>	<b>CLASS</b> 117	<b>GROUP ART UNIT</b> 1792	<b>ATTORNEY DOCKET NO.</b> 061063-0356139	
<b>APPLICANTS</b> Masataka Hourai, Saga-shi, JAPAN; Wataru Sugimura, Saga-shi, JAPAN; Toshiaki Ono, Saga-shi, JAPAN; <b>** CONTINUING DATA *****</b> This application is a 371 of PCT/JP05/15346 08/24/2005 <b>** FOREIGN APPLICATIONS *****</b> JAPAN 2004-246017 08/25/2004 JAPAN 2005-163152 06/02/2005 JAPAN 2005-239529 08/22/2005 <b>** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **</b> 04/02/2007					
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and /FELISA CARLA HITESHEW/ Acknowledged Examiner's Signature	<input type="checkbox"/> Met after Allowance Initials	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWINGS</b> 12	<b>TOTAL CLAIMS</b> 8	<b>INDEPENDENT CLAIMS</b> 2
<b>ADDRESS</b> PILLSBURY WINTHROP SHAW PITTMAN, LLP P.O. BOX 10500 MCLEAN, VA 22102 UNITED STATES					
<b>TITLE</b> Silicon wafer, method for manufacturing the same and method for growing silicon single crystals					
<b>FILING FEE RECEIVED</b> 900	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		